

PATENT ABSTRACTS OF JAPAN

(11)Publication number :

2002-263554

(43)Date of publication of application : 17.09.2002

(51)Int.CI.

B05C 11/08

G03F 7/16

H01L 21/027

(21)Application number : 2001-060969

(71)Applicant : TOKYO ELECTRON LTD

(22)Date of filing : 05.03.2001

(72)Inventor : SADA TETSUYA

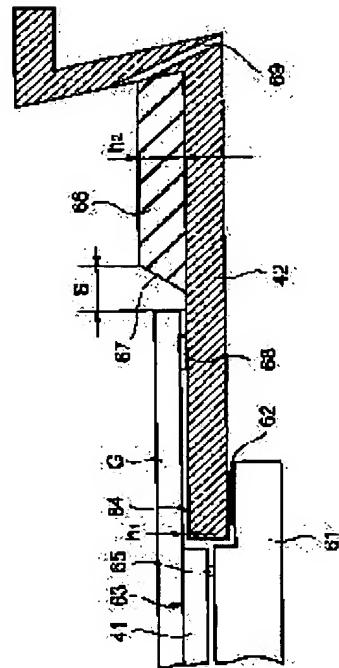
HASHIMOTO HIROSHI

(54) LIQUID SUPPLYING APPARATUS

(57)Abstract:

PROBLEM TO BE SOLVED: To provide a liquid supplying apparatus capable of avoiding occurrence of defects such as cracking of a substrate, preventing mist-like stain formation in the rear face of a substrate and preventing a supplied liquid from flowing around to the rear face of the substrate.

SOLUTION: The floor face 64 of a rotation cup 42 is lowered than a substrate holding face 63 of a spin chuck 41 by 0.2-0.4 mm and a plate 66 is installed so as to face to the outer circumference along the outer circumference of a substrate G, so that stain formation in the rear face of the substrate G owing to mist or the like can be prevented. Moreover, a resist solution or the like is prevented from entering in the gap between them. Further, the substrate G is kept from contact with the floor face 54 when the spin chuck 41 is moved down, so that the substrate is protected from defects such as cracking or the like.



LEGAL STATUS

[Date of request for examination] 12.02.2003

[Date of sending the examiner's decision of rejection]

[Kind of final disposal of application other than the examiner's decision of rejection or application converted registration]

[Date of final disposal for application]

[Patent number]

[Date of registration]

[Number of appeal against examiner's decision of rejection]

[Date of requesting appeal against examiner's decision of rejection]

[Date of extinction of right]

Copyright (C); 1998,2003 Japan Patent Office